IN THE CLAIMS:

Claim 1 (original): A surface acoustic wave device comprising a piezoelectric substrate and an IDT that is formed on said piezoelectric substrate and is made from Al or alloy including Al as a main component, an excited wave being an SH wave, wherein

said piezoelectric substrate is a quartz flat plate where a cut angle θ of a rotation Y cut quartz substrate is set in a range of -64.0°< θ <-49.3° in a counterclockwise direction from a crystal Z-axis, and a propagation direction of a SAW is set to $(90^{\circ}\pm5^{\circ})$ to a crystal X-axis, and

when a wavelength of the SAW to be excited is represented as λ , an electrode film thickness H/ λ standardized by a wavelength of said IDT is set to satisfy 0.04<H/ λ <0.12.

Claim 2 (original): The surface acoustic wave device according to claim 1, wherein a relationship between the cut angle θ and the electrode film thickness H/ λ satisfies - $1.34082 \times 10^{-4} \times \theta^3$ - $2.34969 \times 10^{-2} \times \theta^2$ - $1.37506 \times \theta$ -26.7895 <H/ λ <- $1.02586 \times 10^{-4} \times \theta^3$ - $1.73238 \times 10^{-2} \times \theta^2$ - $0.977607 \times \theta$ -18.3420.

Claim 3 (original): The surface acoustic wave device according to claim 1, wherein, when an electrode finger width of electrode fingers constituting said IDT/(electrode finger width + space between electrode fingers) is defined as a line metalization ratio mr, a relationship between the cut angle θ and a product H/ λ ×mr of the electrode film thickness and the line metalization ratio satisfies -8.04489×10⁻⁵× θ ³-1.40981×10⁻²× θ ²-0.825038× θ -16.0737<H/ λ ×mr<-6.15517×10⁻⁵× θ ³-1.03943×10⁻²× θ ²-0.586564× θ -11.0052.

Claim 4 (original): A surface acoustic wave device comprising a piezoelectric substrate and an IDT that is formed on said piezoelectric substrate and is made from Al or alloy including Al as a main component, an excited wave being utilized as an SH wave, wherein

said piezoelectric substrate is a quartz flat plate where a cut angle θ of a rotation Y cut quartz substrate is set to satisfy a range of $-61.4^{\circ}<\theta<-51.1^{\circ}$ in a counterclockwise direction from a crystal Z-axis, and a propagation direction of a SAW is set to $(90^{\circ}\pm5^{\circ})$ to a crystal X-axis, and

when a wavelength of the SAW to be excited is represented as λ , an electrode film thickness H/ λ standardized by a wavelength of the IDT is set to satisfy 0.05<H/ λ <0.10.

Claim 5 (original): The surface acoustic wave device according to claim 4, wherein a relationship between the cut angle θ and the electrode film thickness H/ λ satisfies - 1.44605×10⁻⁴× θ ³-2.50690×10⁻²× θ ²-1.45086× θ -27.9464<H/ λ <-9.87591×10⁻⁵× θ ³-1.70304×10⁻²× θ ²-0.981173× θ -18.7946.

Claim 6 (original): The surface acoustic wave device according to claim 4, wherein when an electrode finger width of electrode fingers constituting said IDT/(electrode finger width + space between electrode fingers) is defined as a line metalization ratio mr, a relationship between the cut angle θ and a product H/ λ ×mr of the electrode film thickness and the line metalization ratio satisfies -8.67632×10⁻⁵× θ ³-1.50414×10⁻²× θ ²-0.870514× θ -16.7678<H/ λ ×mr<-5.92554×10⁻⁵× θ ³-1.02183×10⁻²× θ ²-0.588704× θ -11.2768.

Claim 7 (original): The surface acoustic wave device according to any one of claims 1 to 6, wherein

said surface acoustic wave device is a one-port surface acoustic wave resonator where at least one IDT is disposed on said piezoelectric substrate.

Claim 8 (original): The surface acoustic wave device according to any one of claims 1 to 6, wherein

said surface acoustic wave device is a two-port surface acoustic wave resonator where at least two IDTs are disposed along a propagation direction of a surface acoustic wave on said piezoelectric substrate.

Claim 9 (original): The surface acoustic wave device according to any one of claims 1 to 6, wherein

said surface acoustic wave device is a lateral coupling type multi-mode filter where a plurality of surface acoustic wave resonators are disposed in proximity to each other in

parallel with a propagation direction of a surface acoustic wave on said piezoelectric substrate.

Claim 10 (original): The surface acoustic wave device according to any one of claims 1 to 6, wherein

said surface acoustic wave device is a vertical coupling type multi-mode filter where two-port surface acoustic wave resonators comprising a plurality of IDTs are disposed along a propagation direction of a surface acoustic wave on said piezoelectric substrate.

Claim 11 (original): The surface acoustic wave device according to any one of claims 1 to 6, wherein

said surface acoustic wave device is a ladder type surface acoustic wave filter where a plurality of surface acoustic wave resonators are connected on said piezoelectric substrate in a ladder shape.

Claim 12 (original): The surface acoustic wave device according to any one of claims 1 to 6, wherein

said surface acoustic wave device is a transversal SAW filter where a plurality of IDTs propagating a surface acoustic wave bidirectionally are disposed on said piezoelectric substrate at predetermined intervals.

Claim 13 (original): The surface acoustic wave device according to any one of claims 1 to 6, wherein

said surface acoustic wave device is a transversal SAW filter where at least one IDT propagating a surface acoustic wave in one direction is disposed on said piezoelectric substrate.

Claim 14 (original): The surface acoustic wave device according to any one of claims 1 to 6, wherein

said surface acoustic wave device is a surface acoustic wave sensor.

Claim 15 (currently amended): The surface acoustic wave device according to any one of claims 1 to [[14]] 6, wherein

said surface acoustic wave device has grating reflectors on both sides of an IDT.

Claim 16 (currently amended): A module device or an oscillation circuit using the surface acoustic wave device according to any one of claims 1 to [[15]] $\underline{6}$.